

jc849 U.S. PTO
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Docket No. 4714 P1/AMI-00-11

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application
Assistant Commissioner for Patents
Washington, D.C. 20231

Re: Inventors: Ming Xi, Ashok Sinha, Moris Kori, Alfred W. Mak, Jeong Soo Byun, Lawrence Chung-Lai Lei, Hua Chung
Title: METHOD AND APPARATUS FOR DEPOSITING REFRACTORY METAL LAYERS EMPLOYING SEQUENTIAL DEPOSITION TECHNIQUES TO FORM A NUCLEATION LAYER

Transmitted herewith is the patent application identified above, including:

- ☒ Specification, claims and abstract, totaling 15 pages, excluding Title Sheet.
- ☒ Drawings totaling 9 pages, ☐ Formal ☒ Informal.
- ☒ Declaration and Power of Attorney (unsigned)
- ☒ Assignment of the invention to Applied Materials, Inc. (unexecuted)
- ☒ Assignment Recordation Cover Sheet

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FEE CALCULATION					
Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims 20	20	20-20=0	0	X \$	--
Independent Claims	4	4	0	\$ 0	\$0
Basic Filing Fee				\$0	\$0
TOTAL FEES					

- ☐ The Commissioner is hereby authorized to charge \$0 to Deposit Account No.
- ☒ Do not charge any fees at this time.
- ☐ The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074. A duplicate copy of this transmittal is enclosed.
- ☒ Please address all future correspondence to:
**PATENT COUNSEL
APPLIED MATERIALS, INC.
Legal Affairs Department
P.O. BOX 450A
Santa Clara, CA. 95052**

I hereby certify that this correspondence, and any correspondence referred to herein, is being deposited with the United States Postal Service as express mail in an envelope addressed to: Box Patent Application, Assistant Commissioner for Patents, Washington, D.C. 20231.

Express Mail Receipt No. EK 767460232 US
Date of Deposit October 3, 2000
Signature: Kenneth C. Brooks

Respectfully submitted,
Kenneth C. Brooks
Kenneth C. Brooks
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